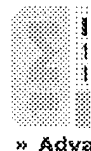


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```
(calibration<or>calibrated<or>
calibrate<or>calibrating)
<paragraph>wafer<and>
(alignment<or>aligning<or>alignmen
```


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[Abstract] [PDF Full-Text (560 KB)] IEEE JNL



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```
(calibration<or>calibrated<or>
calibrate<or>calibrating)
<paragraph>wafer<and>
(pattern<or>patterns<or>crucif
```


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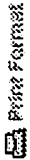
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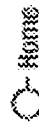
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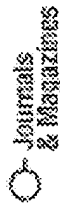
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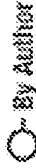
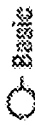
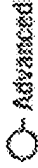
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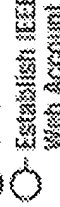
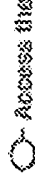
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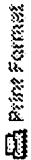
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